

Process:	D-POLY/SMALL FLOW
Equipment ID	DF-PLD-09
Model	ALPHA-3031-K
Item	Detail
General Configuration	
Process	D-Poly-Small FLOW
Tool Mode	ALPHA-3031-K
OEM Serial #	L000005Y5359
Process Pressure	73Pa, 133Pa
Process Temperature	510C, 525C, 530C
Boat Operation	2 Boats Type
Carrier I/D Reader/Writer	Read (at Load Port) Write (at Load Port) (OP)
Maker /Model	ASYST / ATR9100
Furnace Unit	
Heater Type	Mid-Temp. VMM-56-002 5zone / 500-1000(c)
T/C for Over temperature Protection	KIT,CHAMBER O.H.SNSR
Temperature Controller	MA901-8FK09-Z250A
Wafer / Carrier Handling	
Wafer Type	300 SEMI STD-Notch
Wafer Notch Aligner	Not Installed (STD)
Carrier Type	FOUP / 25slots (STD)
Carrier Maker/Type	Pending
Carrier Storage Qty.	16
Fork Type/Material	1+4 / Al2O3 (STD)
W/T Wafer I/F speed (U/D)	Standard
Wafer Loading/Unloading Sequence	ED => P => M / M => P => ED
Cap Heater	Not Use
Boat / Pedestal	
Qty. of Production Wafers	100
Boat Material	SiC with CVD-Coat
Boat Type	117 slots Ladder (8mm pitch)
Boat Rotation	Installed
Pedestal Type	Quartz
Process Tube	
Outer / Inner Tube Material	Quartz / Quartz
Inner Type	Sjtraight
Internal T/C Type	Outer Tube interior wall type (for CONV.)
Tube Sealing	O-ring Seal
Quartzware - General	
Quartz Maker Requirement	None

Quartz Provider	See Customized Details
SiC Maker Requirement	None
Sic Provider	Customer
Fab. Constraint	
System Controller	WAVES
Front Operation Panel	Installed (OP)
Front MMI and Gas Flow Chart	MMI & GFC Installed
Signal Tower / Colors	Installed / 4-Color
Signal Tower location(s)	See Customized Details
General Pressure Display Units	Pressure-Mpa / Vac-Torr
Gas Cabinet Exhaust Display Units	SI (Pa)
Furnace Temperature Controller	M560A
Vacuum System	
Vacuum Exhaust System	New Type
Pump	Pending
Pump Provided by	Customer
Pump Power	Customer's Facility Provided
N2 Gas panel for Pump Provided By	Customer
Pump-FNC vac Tubing provided by	Customer (STD)
Vacuum Pressure Controller	CKD VEC
Vacuum Gage - Pressure Ctrl	MKS Capacitance Manometer
Vacuum Gage - Press. Monitor(133kpa)	MKS Capacitance Manometer
Vacuum Gage - Pump Monitor	MKS Capacitance Manometer
Main valve	CKD VEC
Trap	Not installed
Gas Distribution System	
Basic Style	Integrated Gas system
Tubing	Stainless steel / Electrical-polish(STD)
Tubing Bends	No Bend (OP)
Tube heating (Include Vacuum Line)	Use
Manual Valve	Fuijkin
Air-Operated Valve	Fuijkin
Filter	MYKROLIS
Regulator	VERIFLO
Press. Transducer	MYKROLIS
Soft Backfill Injector	Installed (OP)
Manifold Heater	Not Use
Liquid Source Operation System	None
Liquid Source Auto-Refill	None (STD)
Auto-Refill Provided By	N/A
Auto-Refill Tubing Interconnect By	N/A
MFCs	SiH4 = 3 slm
	PH3 = 500 sccm
	PH3 = 50 sccm
	PH3 = 30 sccm
	ClF3 = 5 slm

	N2 = 3 slm
	N2 = 5 slm X4